

PARAMETRIC STUDIES FOR TUNING FORK MEMS GYROSCOPE

**V.U.SHREE, P.R.RAO, P.C.S.REDDY,
M.SREENIVASULU, P.SRIKANTH AND M.ARUNKUMAR**

Abstract

In this paper variations in Micro-Electro-Mechanical-System (MEMS) sensors gyroscope suspension design have been explored. Designs that utilize in-plane and out-of-plane sensing and resonant frequency are studied Design and analysis of poly-silicon gyroscopes have been carried out.

Keywords : In-plane and out-of-plane stiffness, resonant frequency , MEMS gyroscope